



*IFWA*

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

MIMURA, *et al.*

Serial No.: 10/647,433

Filed: 26 August 2003

For: SILICON ETCHING METHOD

Art Unit: 1765

Examiner: Tran, Binh X.

Atty. Dckt: 033082M172

**PETITION FOR A THREE-MONTH EXTENSION OF TIME**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This is a Petition for Extension of Time for a three-month period. This Petition for Extension of Time is being concurrently filed with a Response.

Payment by credit card online in the amount of \$1,020.00 is submitted herewith.

Respectfully submitted,  
SMITH, GAMBRELL & RUSSELL, LLP

Michael A. Makuch  
Reg. No. 32,263

Date: April 5, 2006

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